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(12) **United States Design Patent**  
**Sekiguchi et al.**

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(54) **PROFILOMETER**

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(\*\*) Term: **14 Years**

(21) Appl. No.: **29/366,648**

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(51) **LOC (9) Cl.** ..... **15-09**

(52) **U.S. Cl.** ..... **D15/122**

(58) **Field of Classification Search** ..... D15/122;  
33/174, 503, 551, 558, 558.4, 573; 73/105;  
250/491.1, 492.2; 356/4.01, 73, 369, 497,  
356/511, 601; 367/120, 138; 702/167  
See application file for complete search history.

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(57) **CLAIM**

We claim the ornamental design for a profilometer, as shown and described.

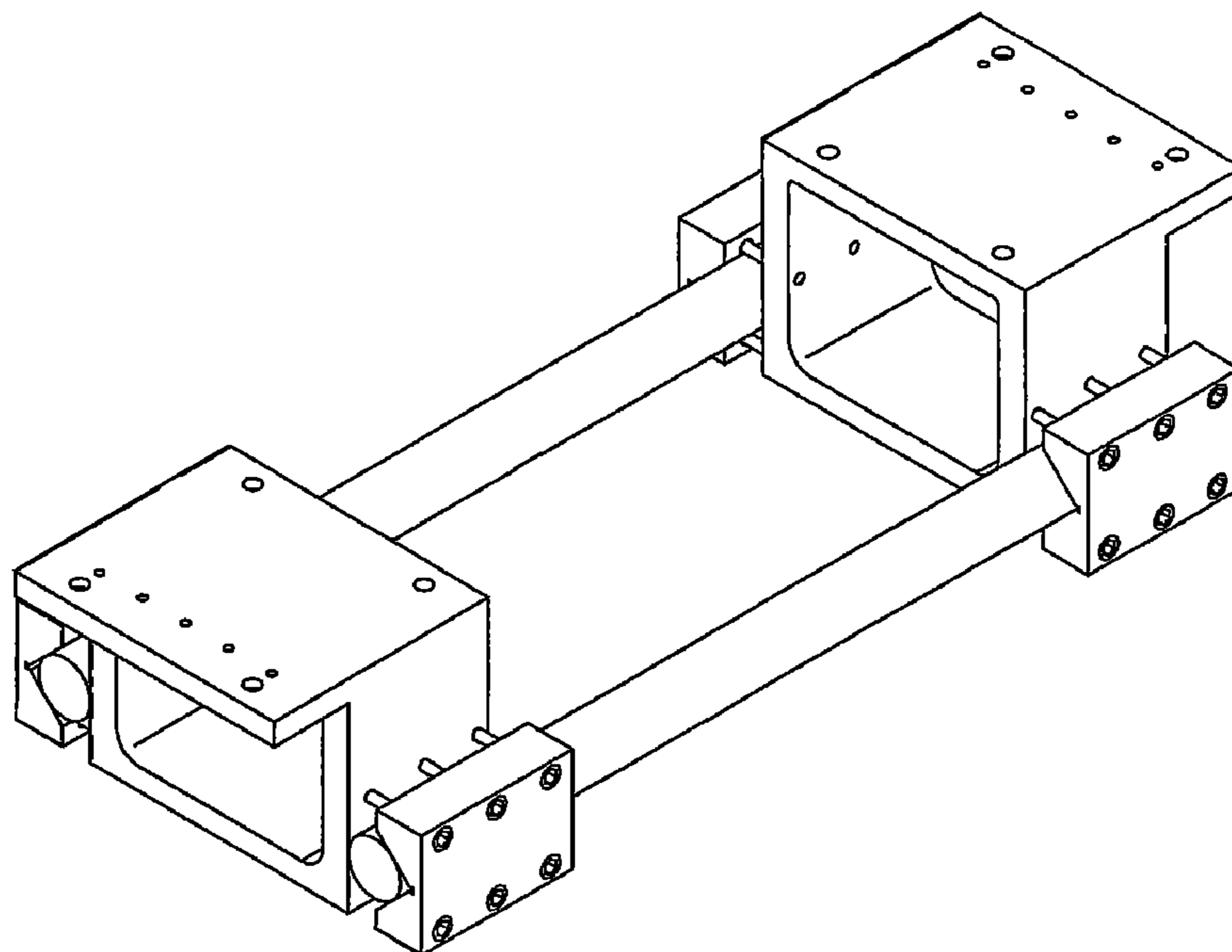
**DESCRIPTION**

FIG. 1 is a perspective view of a profilometer;  
FIG. 2 is a front view thereof;  
FIG. 3 is a left-side view thereof;  
FIG. 4 is a right-side view thereof;  
FIG. 5 is a top plan view thereof;  
FIG. 6 is a back view thereof;  
FIG. 7 is an enlarged view of portion 7-7 of FIG. 2;  
FIG. 8 is an enlarged view of portion 8-8 of FIG. 3;  
FIG. 9 is an enlarged view of portion 9-9 of FIG. 4;  
FIG. 10 is an enlarged view of portion 10-10 of FIG. 5;  
FIG. 11 is an enlarged view of portion 11-11 of FIG. 6;  
FIG. 12 is an enlarged view of portion 12-12 of FIG. 1;  
FIG. 13 is a perspective view of the profilometer; and,  
FIG. 14 is an illustrative view of the profilometer thereof removed to disclose details not otherwise visible.

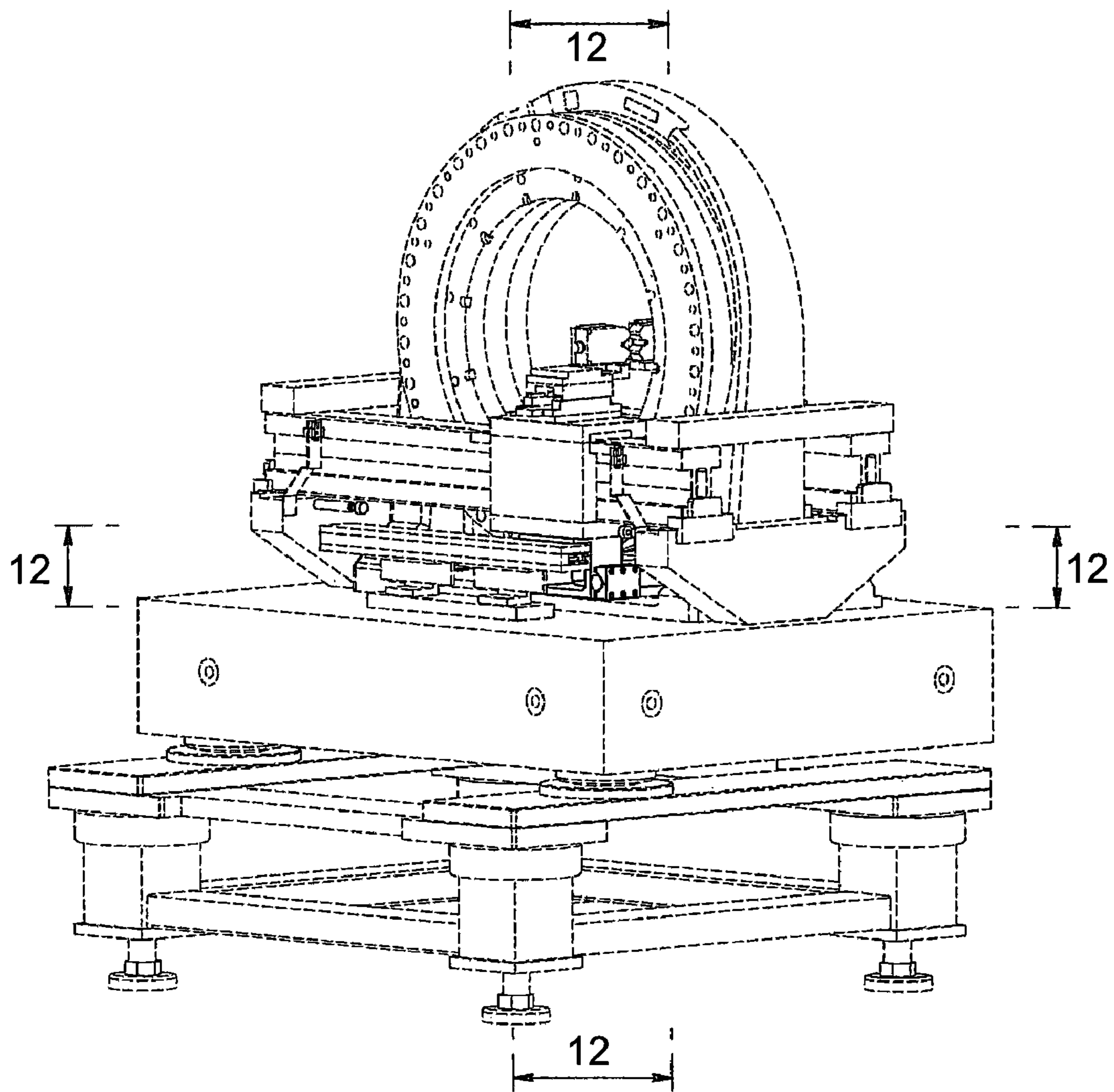
The subject article is a profilometer used for measuring a surface profile (such as the extent of flatness) of a thin disk object (such as a silicon wafer).

The broken lines in the drawings depict unclaimed environmental subject matter.

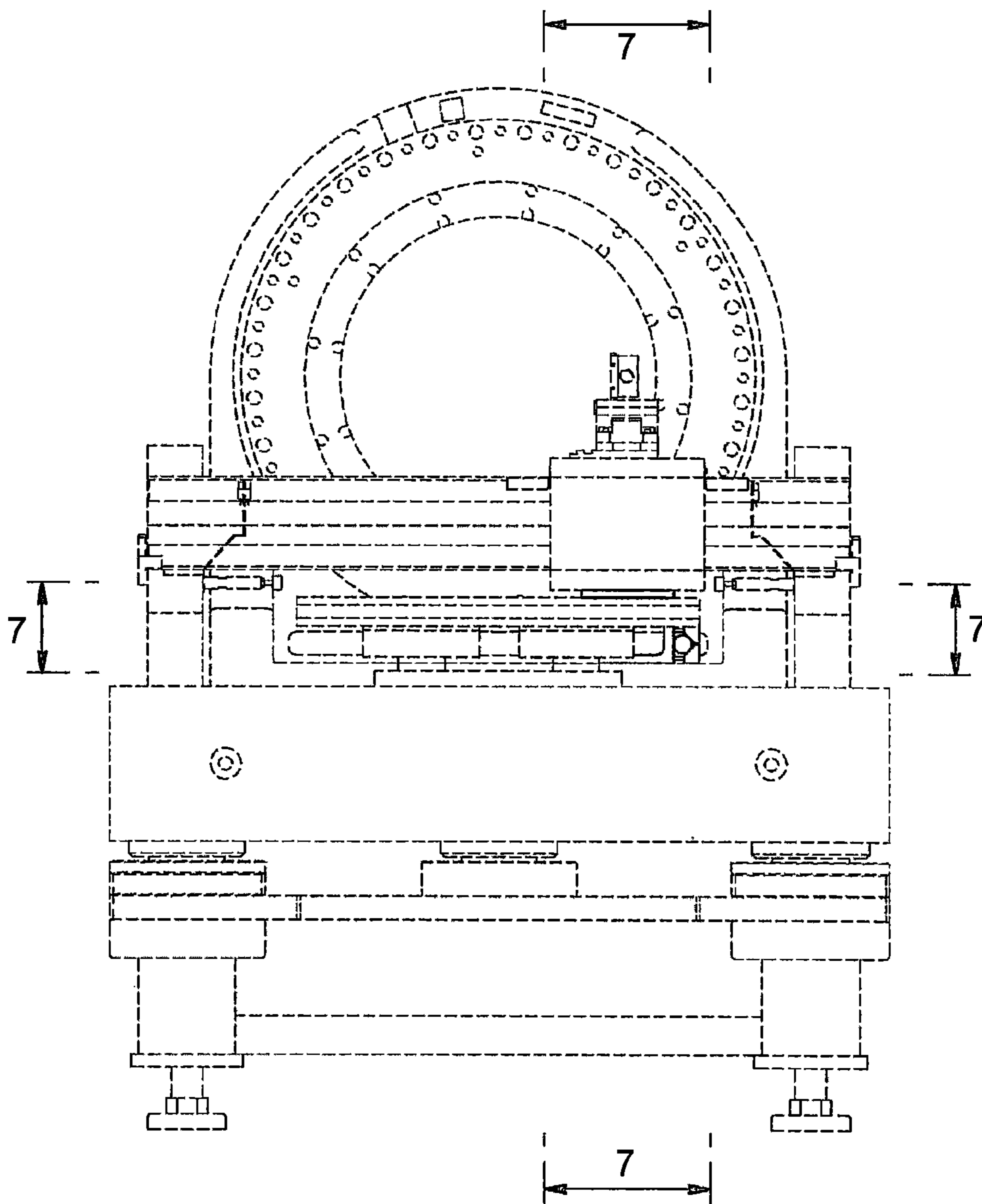
**1 Claim, 11 Drawing Sheets**



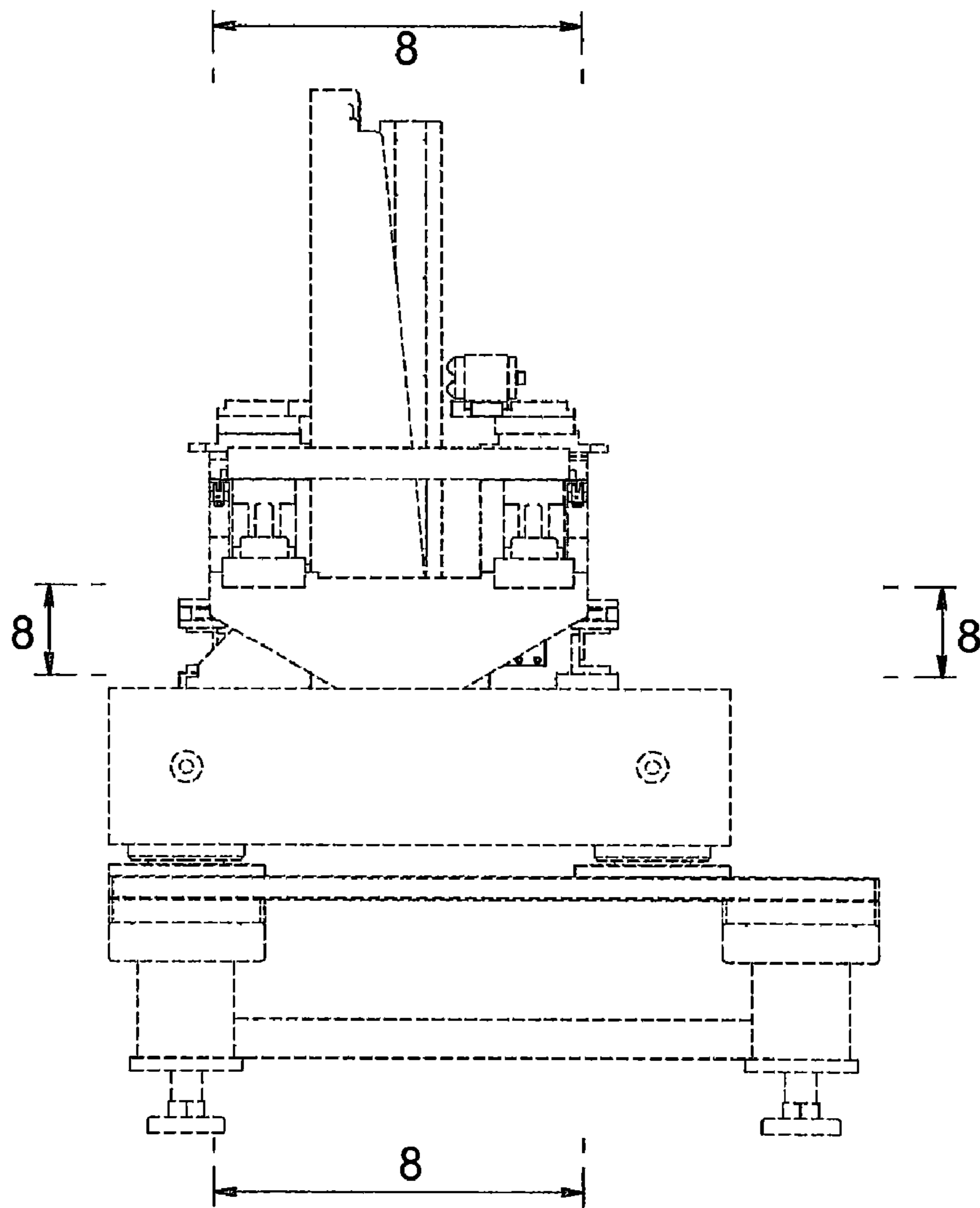
*Fig. 1*



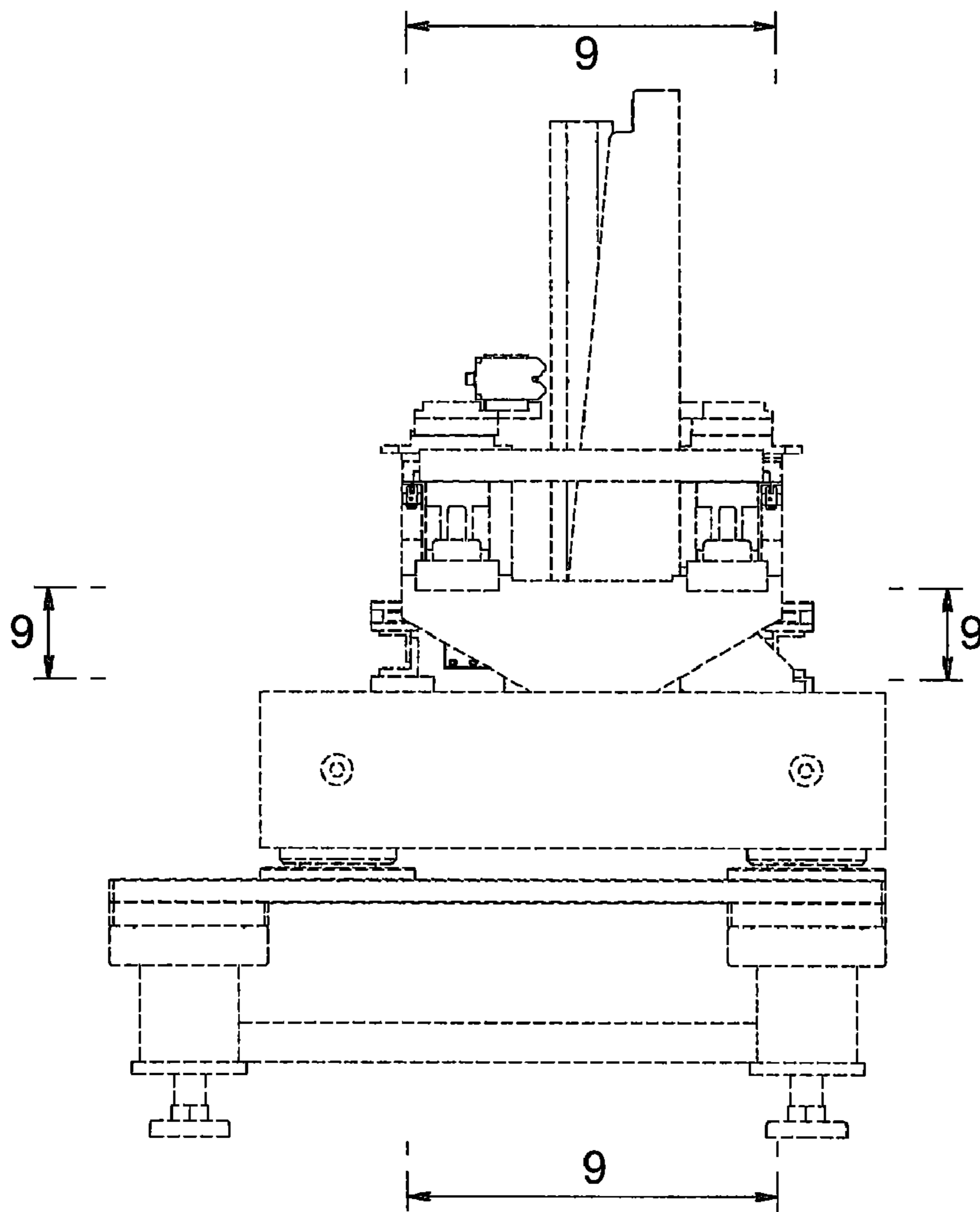
*Fig.2*



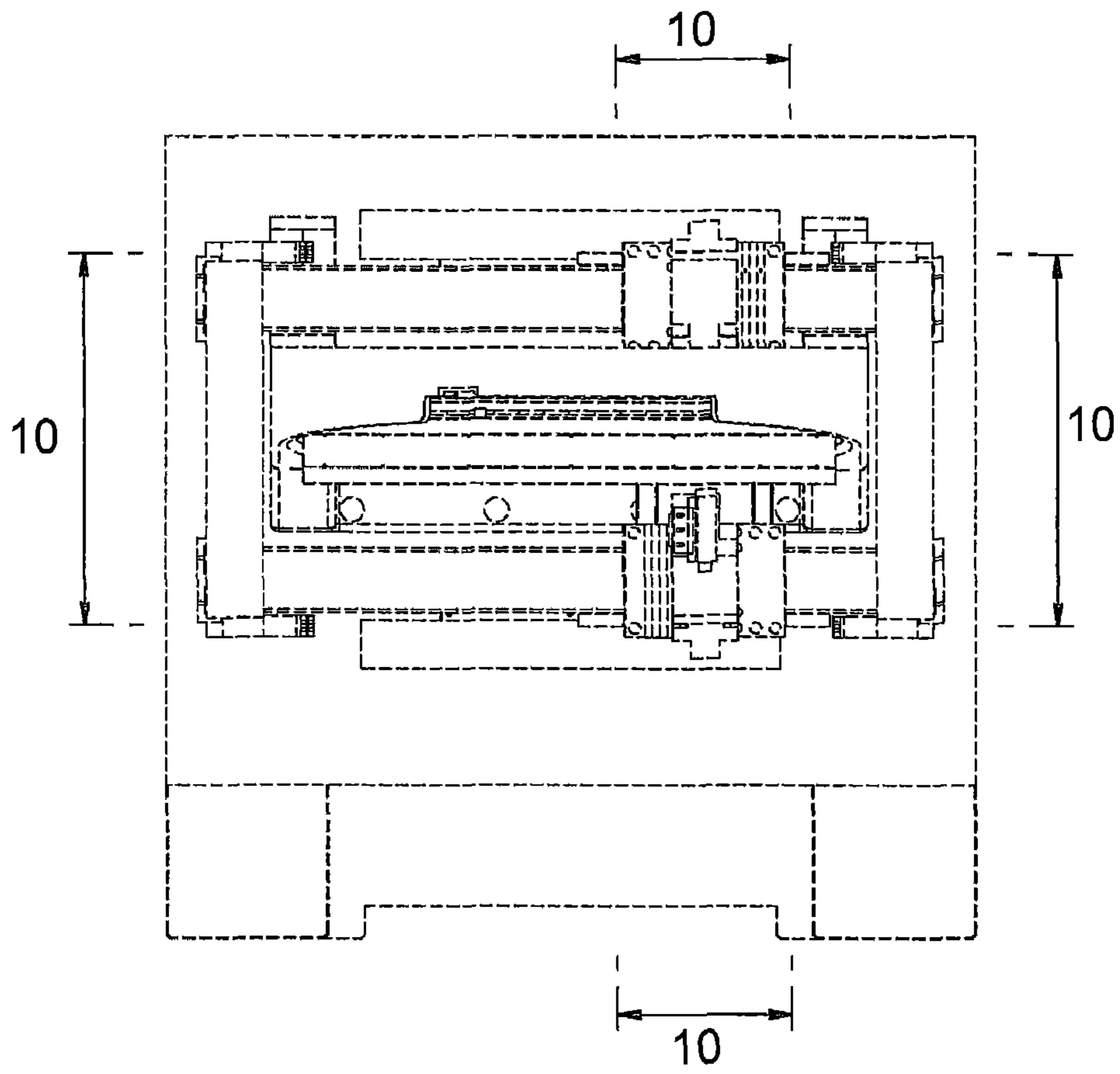
*Fig. 3*



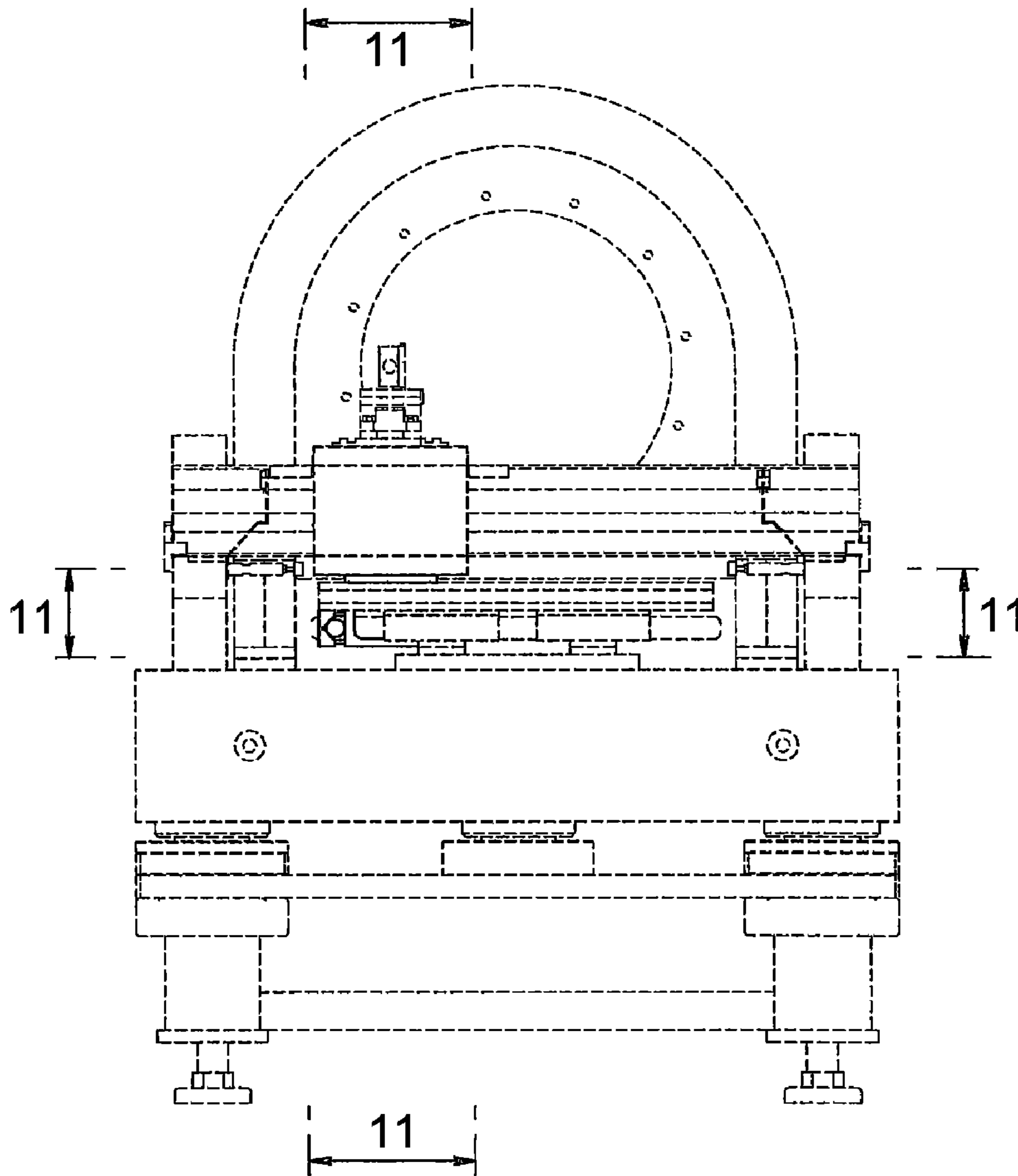
*Fig.4*



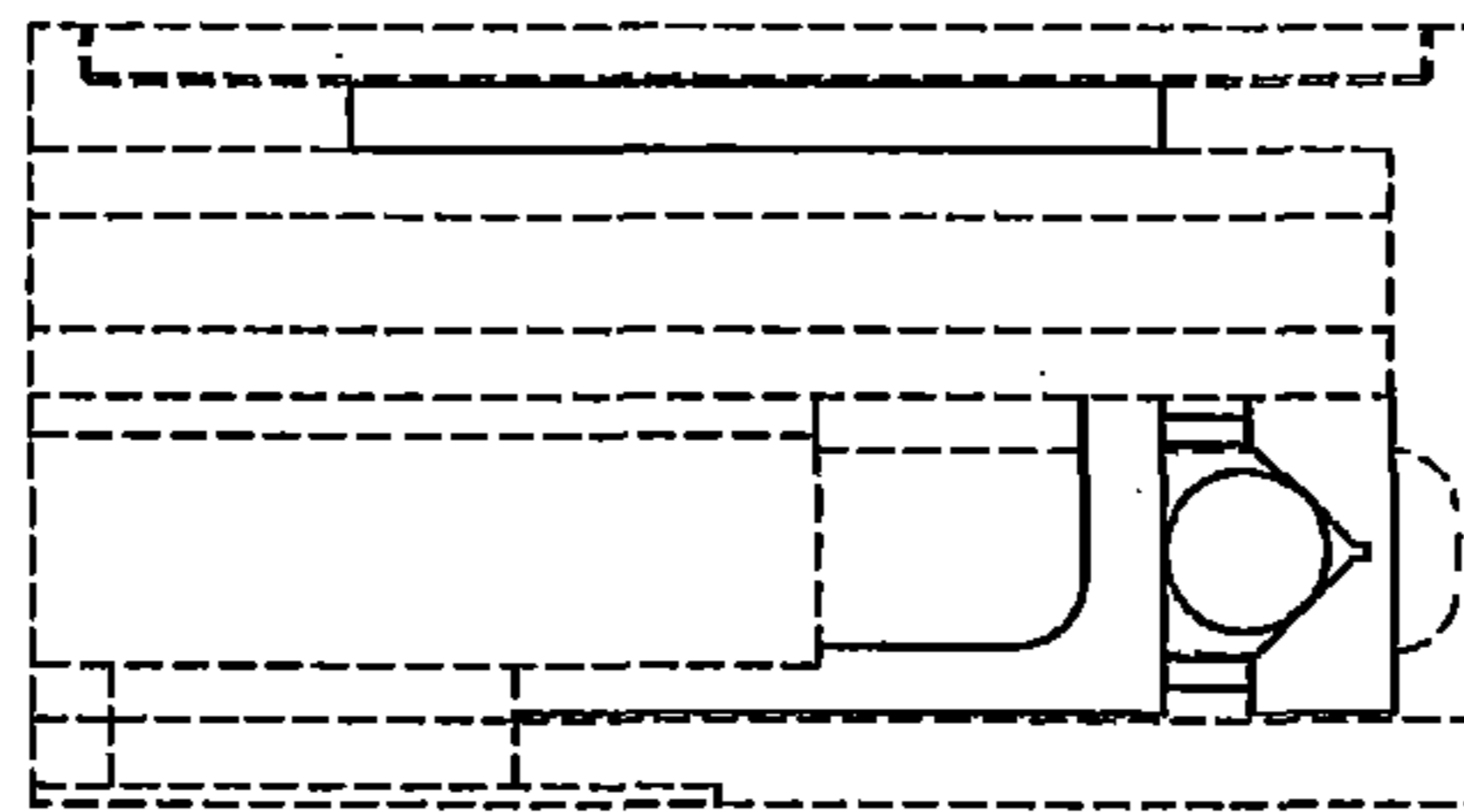
*Fig.5*



*Fig.6*



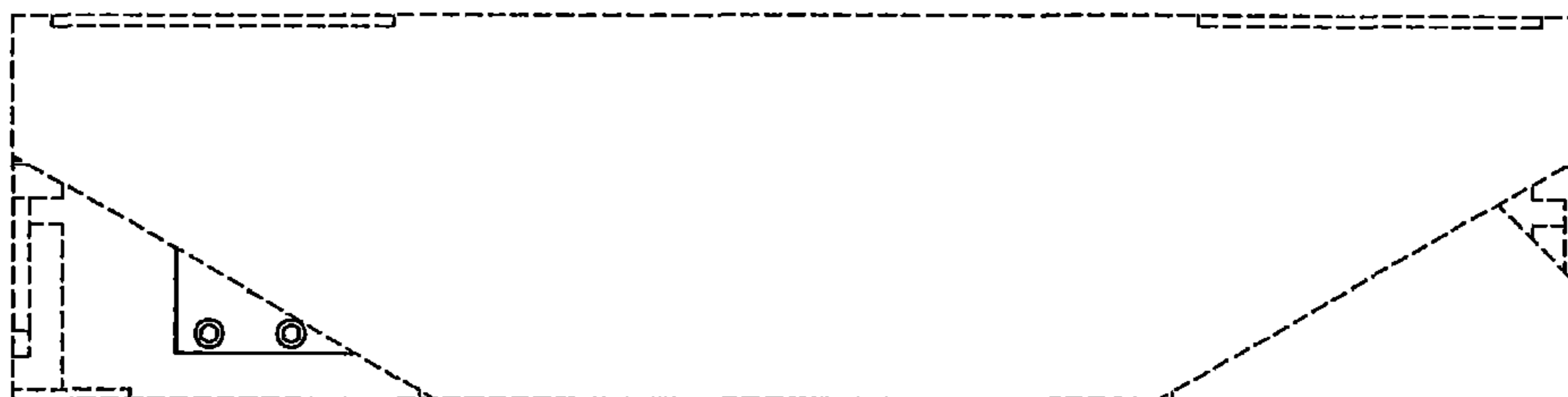
*Fig.7*



*Fig.8*

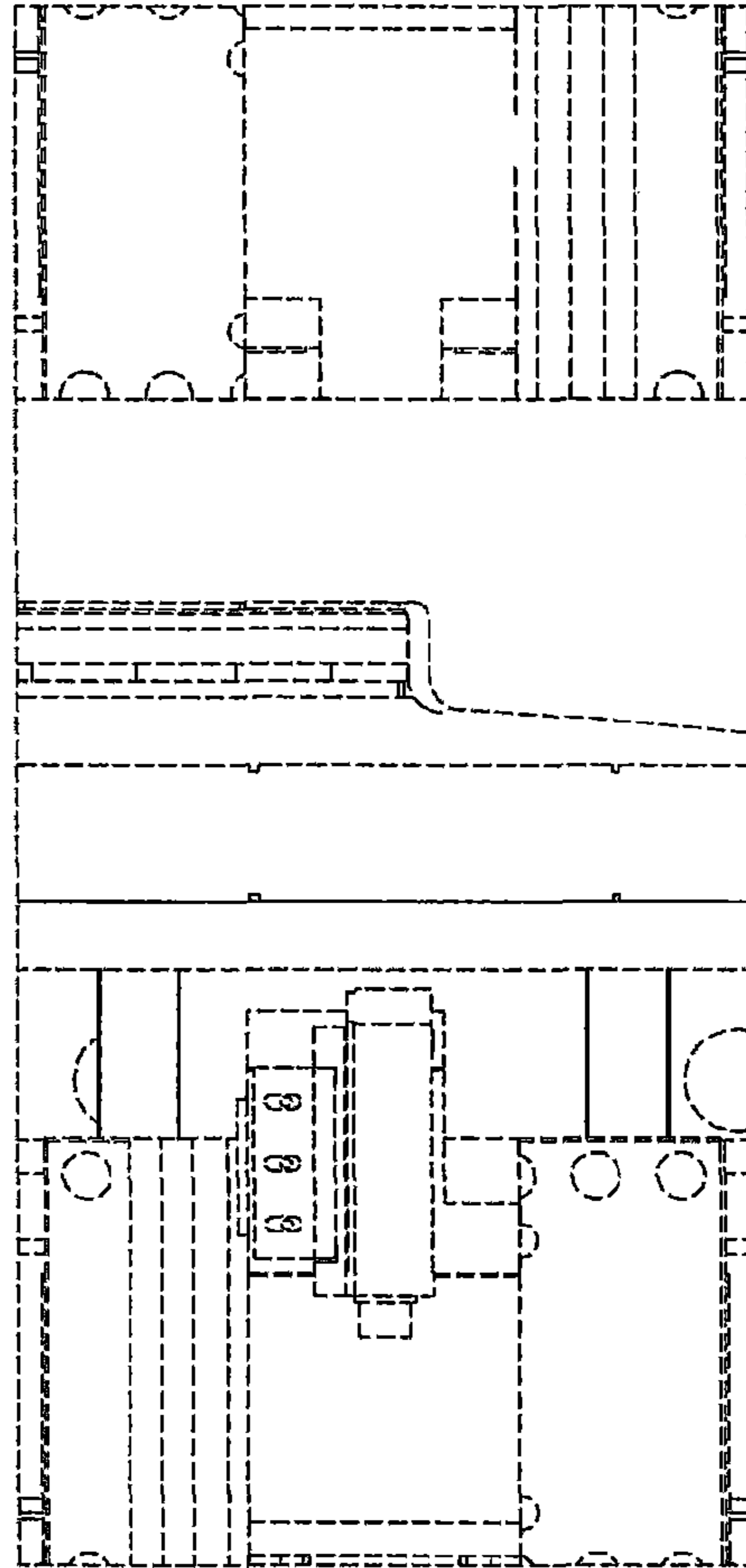


*Fig.9*

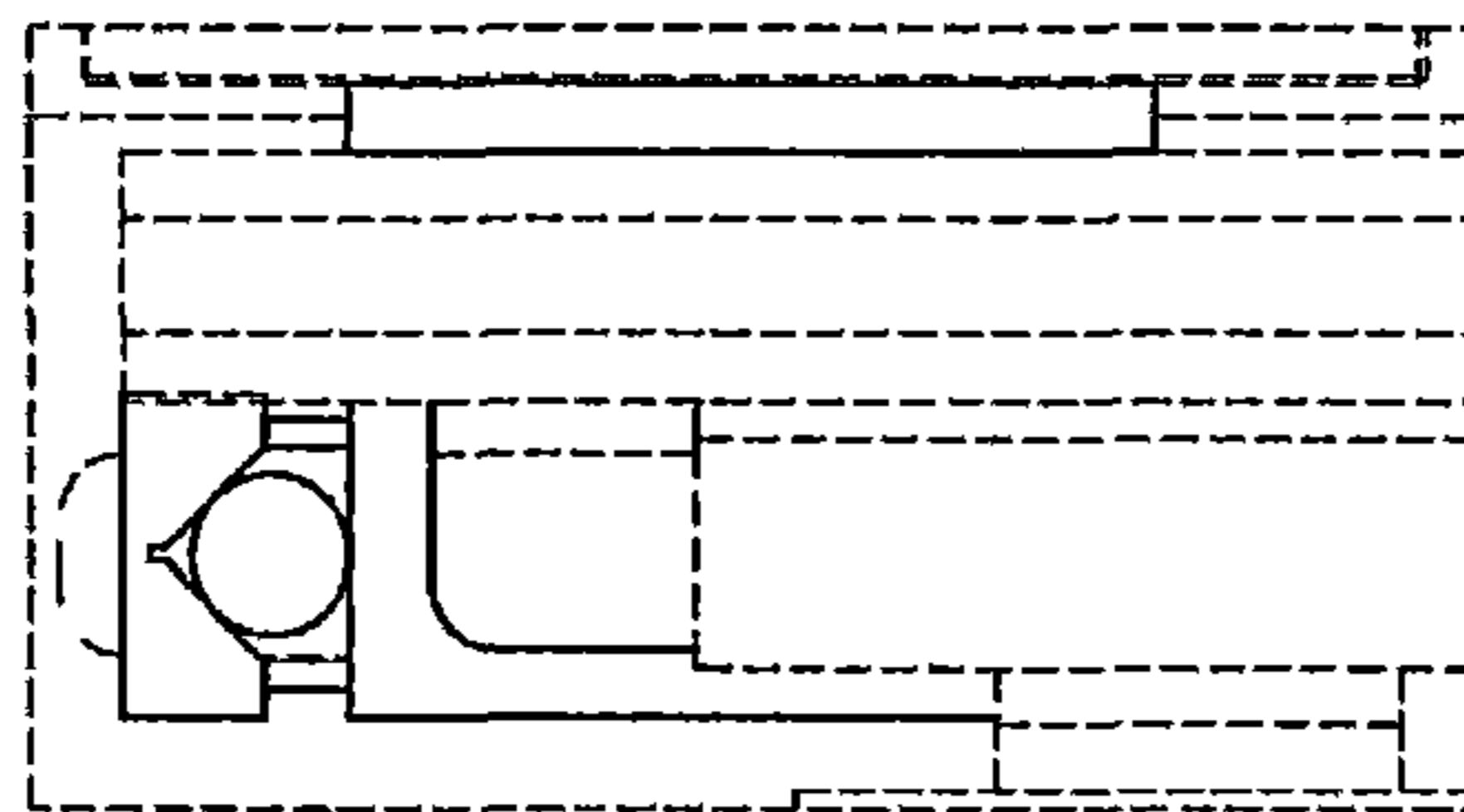




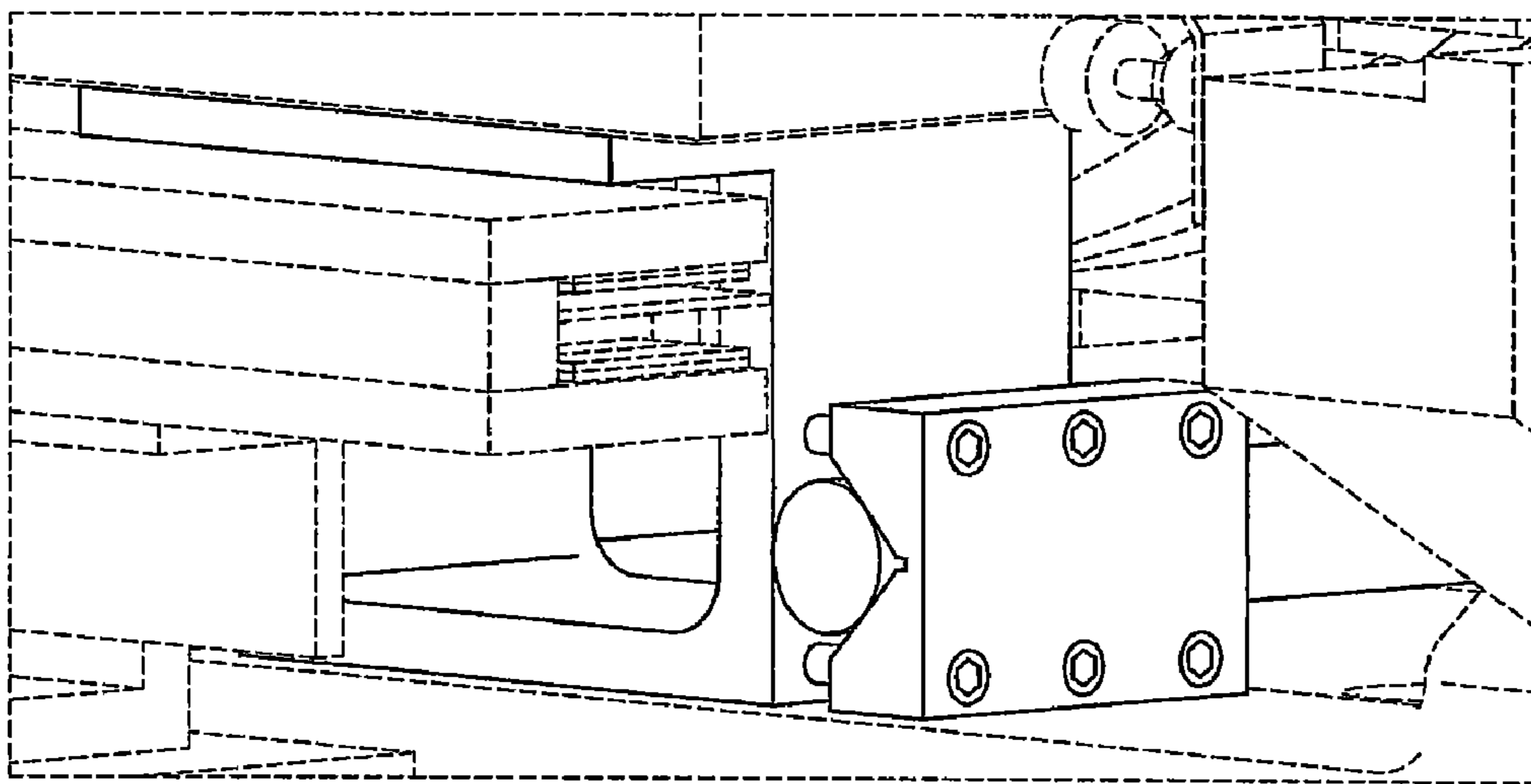
*Fig. 10*



*Fig. 11*



*Fig. 12*



*Fig. 13*

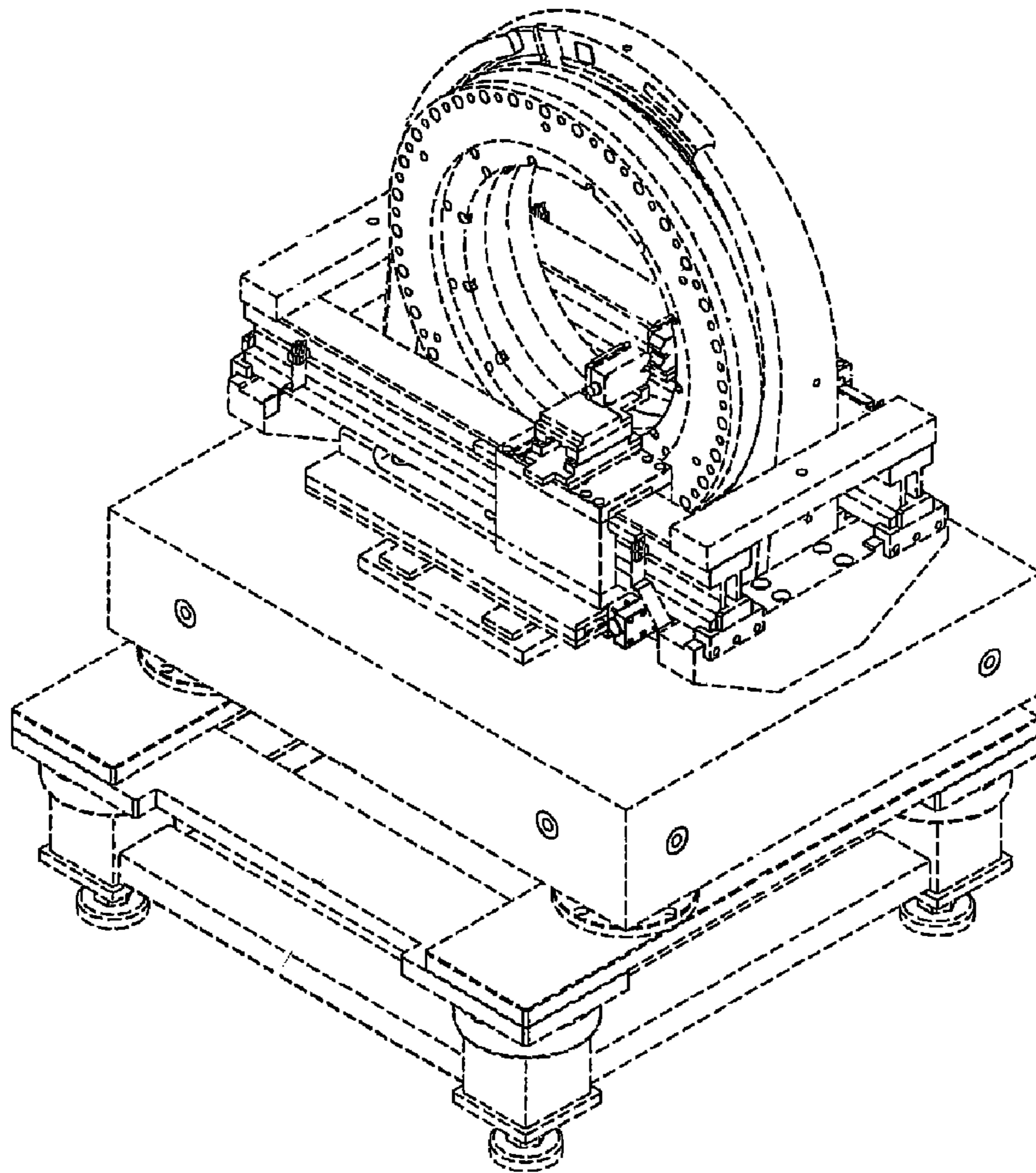


Fig. 14

